[TS03W2]

Nanomanufacturing and Metrology Technologies 2

Date & Time	July 8(Wed.), 2026 / 15:50-17:50
Place	Room 209B
Session Chair(s)	Dr. Soongeun Kwon (KIMM), Dr. Hyun-Mi Kim (KETI)

TS03W2_I_1 ***Invited** 15:50-16:20

Self-Rectifying Memristors for Scalable Nanomanufacturing: From Interface Engineering to Reliable In-Memory and Neuromorphic Computing

Nan Du[1,2]
([1]Leibniz Institute of Photonic Technology, [2]Leibniz Institute of Photonic Technology)

TS03W2_I_2 ***Invited** 16:20-16:50

Interfacial Engineering of Two-Dimensional Layered Materials for Multifunctional Electronic Systems

Kyungjune Cho
(Korea Institute of Science and Technology)

TS03W2_I_3 ***Invited** 16:50-17:20

Laser-Induced Graphene Formation on Lignocellulosic Materials

Han Ku Nam
(Chungnam National University)

TS03W2_I_4 ***Invited** 17:20-17:50

AI-Driven Metrology and Automated Analysis Framework for Atomic Layer Deposition

Jihye Seo[1], Sung Kyu Jang[1], Jihun Kim[1,2], Hyun-Mi Kim[1], Sun Gil Kim[1], Jong Hyun Choi[1], and Hyeongkeun Kim[1]
([1]Korea Electronics Technology Institute, [2]Sungkyunkwan University)